PCE

Attorney Docker OSP-15115

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:

Confirmation Number: 5650

SHIOTA et al.

Group Art Unit: 1722

Application No.: 10/706,266

Filed: November 13, 2003 Examiner: Kunemund, Robert M.

Title: SILICON WAFER AND MANUFACTURING METHOD THEREOF

AMENDMENT WITH REQUEST FOR CONTINUED EXAMINATION UNDER 37 C.F.R. §1.114

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In reply to the Notice of Non-Compliant Amendment dated March 31, 2006, please amend the above-identified application as follows: